



AG/176S
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Docket No. 56775 (70551)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: N. Kanetsuki, et al. EXAMINER: L. Vinh
U.S.S.N.: 10/015,446 ART UNIT: 1765
FILED: 12/12/2001
FOR: Plasma Processing Method

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By: *Eileen Woodbury*

Eileen Woodbury

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

RESPONSE TO FINAL OFFICE ACTION

The following is in response to the Office Action mailed February 24, 2004, in the above referenced application.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.

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